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Docket No.: 209236US0

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

RE: Application Serial No.: 09/867,541  
Applicants: Toshihiro OGAWA, et al.  
Filing Date: May 31, 2001  
For: COMPOSITION FOR POLISHING PAD AND  
POLISHING PAD USING THE SAME  
Group Art Unit: 1711  
Examiner: U. Rajguru

SIR:

Attached hereto for filing are the following papers:

**SUPPLEMENTAL AMENDMENT W/MARKED-UP COPY; LITERATURE ARTICLE:  
FAYOLLE et al.: EVALUATION OF A NEW SLURRY-FREE CMP TECHNIQUE FOR  
OXIDE PLANARIZATION**

Our check in the amount of \$0.00 is attached covering any required fees. In the event any variance exists between the amount enclosed and the Patent Office charges for filing the above-noted documents, including any fees required under 37 C.F.R. 1.136 for any necessary Extension of Time to make the filing of the attached documents timely, please charge or credit the difference to our Deposit Account No. 15-0030. Further, if these papers are not considered timely filed, then a petition is hereby made under 37 C.F.R. 1.136 for the necessary extension of time. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND,  
MAIER & NEUSTADT, P.C.

  
Norman F. Oblon

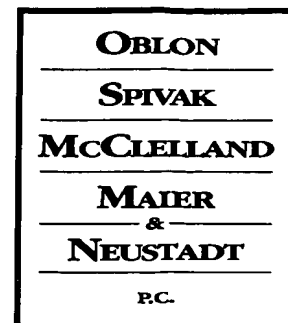
Registration No. 24,618

Harris A. Pitlick  
Registration No. 38,779



22850

(703) 413-3000 (phone)  
(703) 413-2220 (fax)



ATTORNEYS AT LAW

Norman F. Oblon  
(703) 413-3000  
noblon@oblon.com

Harris A. Pitlick  
(703) 413-3000  
hpitlick@oblon.com  
\*Bar Other Than Virginia

209236US-0



IN THE UNITED STATES PATENT & TRADEMARK OFFICE

RE APPLICATION OF

Toshihiro OGAWA ET AL

SERIAL NO: 09/867,541

FILED: MAY 31, 2001

FOR: COMPOSITION FOR POLISHING :  
PAD AND POLISHING PAD  
USING THE SAME

:

: EXAMINER: RAJGURU, U.

:

: GROUP ART UNIT: 1711

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SUPPLEMENTAL AMENDMENT

ASSISTANT COMMISSIONER FOR PATENTS  
WASHINGTON, D.C. 20231

SIR:

#5  
Supplemental to the amendment filed September 9, 2002, Applicants respectfully  
request reconsideration of the above-identified application in view of the following  
amendment and remarks.

IN THE SPECIFICATION

Please replace Table 1 at page 28 with the following:

B1

	Example		Comparative example	
	1	2	1	2
Removal rate (nm/min.)	190	250	60	10
State of a pore	○	○	×	×
Breaking elongation (%)	100	100	>600	>600
Breaking remaining elongation (%)	0	0	510	220